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Docket No.: 4539-0116PUS1

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Ken NAKANISHI

International Application No.: PCT/JP2005/001740

Application No.: NEW

Art Unit: N/A

Filed: August 1, 2006

Examiner: Not Yet Assigned

For: ION DOPING APPARATUS, ION DOPING

METHOD, SEMICONDUCTOR DEVICE AND

METHOD OF FABRICATING SEMICONDUCTOR DEVICE

PRELIMINARY AMENDMENT

MS Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

The following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application.

This amendment includes:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.